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**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

*In re* application of:

Nam P. Suh et al.

Serial No.: 10/029,158

Filed: December 21, 2001

For: **APPARATUS AND METHOD FOR  
CHEMICAL MECHANICAL  
POLISHING OF SUBSTRATES**

Examiner: RACHUBA, Maurina T.

Art Unit: 3723

San Francisco, CA 94111

Date: September 13, 2004

Mail Stop Amendment  
Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

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**AMENDMENT/RESPONSE**

Sir:

In response to the Office Action mailed April 13, 2004, Applicants submit the following amendments and remarks accompanied by a Petition for Extension of Time under 37 CFR 1.136(a) with proper fees, extending the period for response by two (2) month.

**Amendments to the Specification begin on page 2 of this paper.**

Adjustment date: 10/18/2004 LHORAN

**Amendments to the Claims are reflected in the listing of claims which begins on page 4 of this paper.**

2004/09/17 DENRANU1 00000025 10029158

01 FC:1202

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**Amendments to the Drawings begin on page 10 of this paper.**

2004/09/18/2004 LHORAN 00000003 10029158

**Remarks/Arguments begin on page 11 of this paper.**

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09/17/2004 DENRANU1 00000025 10029158

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Repln. Ref: 10/18/2004 LHORAN 0011460900